

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Ki-yeon Park et al.

Serial No.: 10/828,596

Filed: April 21, 2004

For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE FILMS
AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR DEVICES USING
ATOMIC LAYER DEPOSITION

Confirmation No.: 5520

Examiner: Ori Nadav

Group Art Unit: 2811

November 13, 2007

Mail Stop AF
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL

Sir:

The present Amendment is being filed to address the issues raised in the final Office Action dated September 11, 2007.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on Page 12 of this paper.